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PATENT

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent of:

Kazunori IWAMOTO et al.

Application No.: 09/866,600

Filed: May 30, 2001

For: STAGE APPARATUS WHICH SUPPORTS
INTERFEROMETER, STAGE POSITION
MEASUREMENT METHOD, PROJECTION
EXPOSURE APPARATUS, PROJECTION
EXPOSURE APPARATUS MAINTENANCE
METHOD, SEMICONDUCTOR DEVICE
MANUFACTURING METHOD, AND
SEMICONDUCTOR MANUFACTURING
FACTORY

U.S. Patent No. 6,867,849 B2

Issued: March 15, 2005

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450
Attention: Certificate of Correction Branch

LETTER CALLING ATTENTION TO ERRORS IN PATENT

Sir:

Patentees note the following errors in the above-identified patent:

COLUMN 3:

Line 36. "inventor has" should read -- inventors have --.

COLUMN 11:

Line 65, "mark" should read -- bar --.

These errors are relatively insignificant. Therefore, Patentees believe that filing a Request for Certificate of Correction is not warranted. Rather, Patentees request that this paper be placed of record in the official file of the subject patent.

Patentees believe no fee is due for filing this paper. Nevertheless, the Commissioner is authorized to charge Deposit Account No. 06-1205 should any fee be deemed required.

Patentees' undersigned attorney may be reached in our Washington, D.C. Office by telephone at (202) 530-1010. All correspondence should continue to be directed to our below-listed address.

Respectfully submitted,



Attorney for Patentees
Steven E. Warner
Registration No. 33,326

FITZPATRICK, CELLA, HARPER & SCINTO
30 Rockefeller Plaza
New York, New York 10112-3801
Facsimile: (212) 218-2200
SEW/eab